Special Issue

Ultra Precision Technologies for Micromachining

Message from the Guest Editors

Micromachining is a group of advanced technologies that enables microcomponents and/or microstructures to be fabricated with at least one dimension lying in the microscale. It has long been recognized as a powerful tool for high-value manufacturing and has been widely applied across different industrial sectors. Ultraprecision technologies, which are the main thrust of this step-change. They bring significant advantages to micromachining from the aspects of high accuracy and resolution, high complexity, high throughput, low lead time, low investment cost, etc. In this Special Issue, we seek papers in all kinds of ultraprecision technologies with a clear contribution to the advancement of micromachining. Micromachining technologies include but are not limited to mechanical-based technologies such as diamond turning, precision grinding; chemical based technologies such as photolithography, reactive ion etching; physical based technologies such as laser, ion beam, electrical discharge machining; and their hybrids. Original research papers, review articles, and short communications are all welcome.

Guest Editors

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Prof. Dr. Yukui Cai

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Deadline for manuscript submissions

closed (30 June 2020)

Micromachines

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Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Editor-in-Chief

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